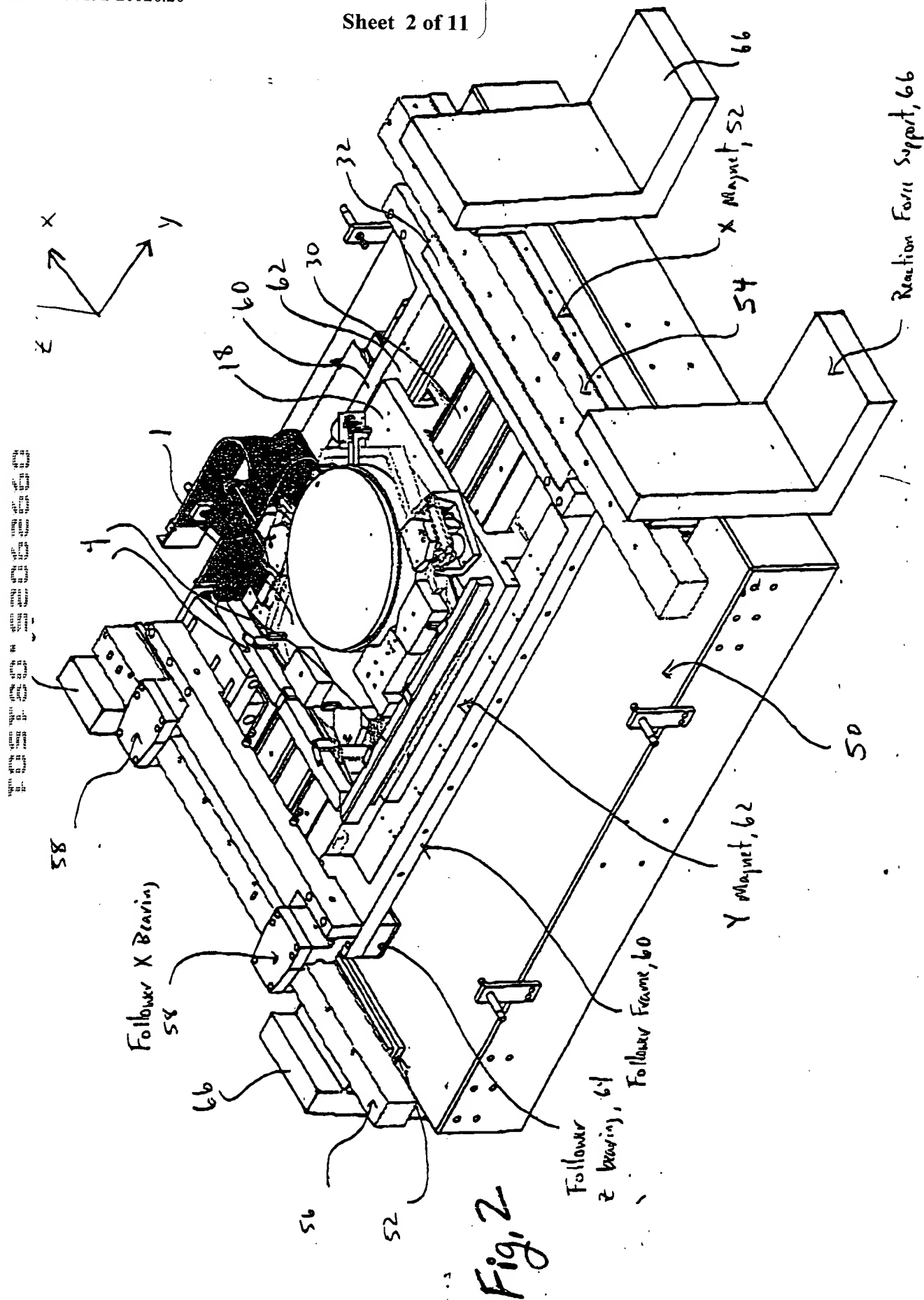


Fig. 1



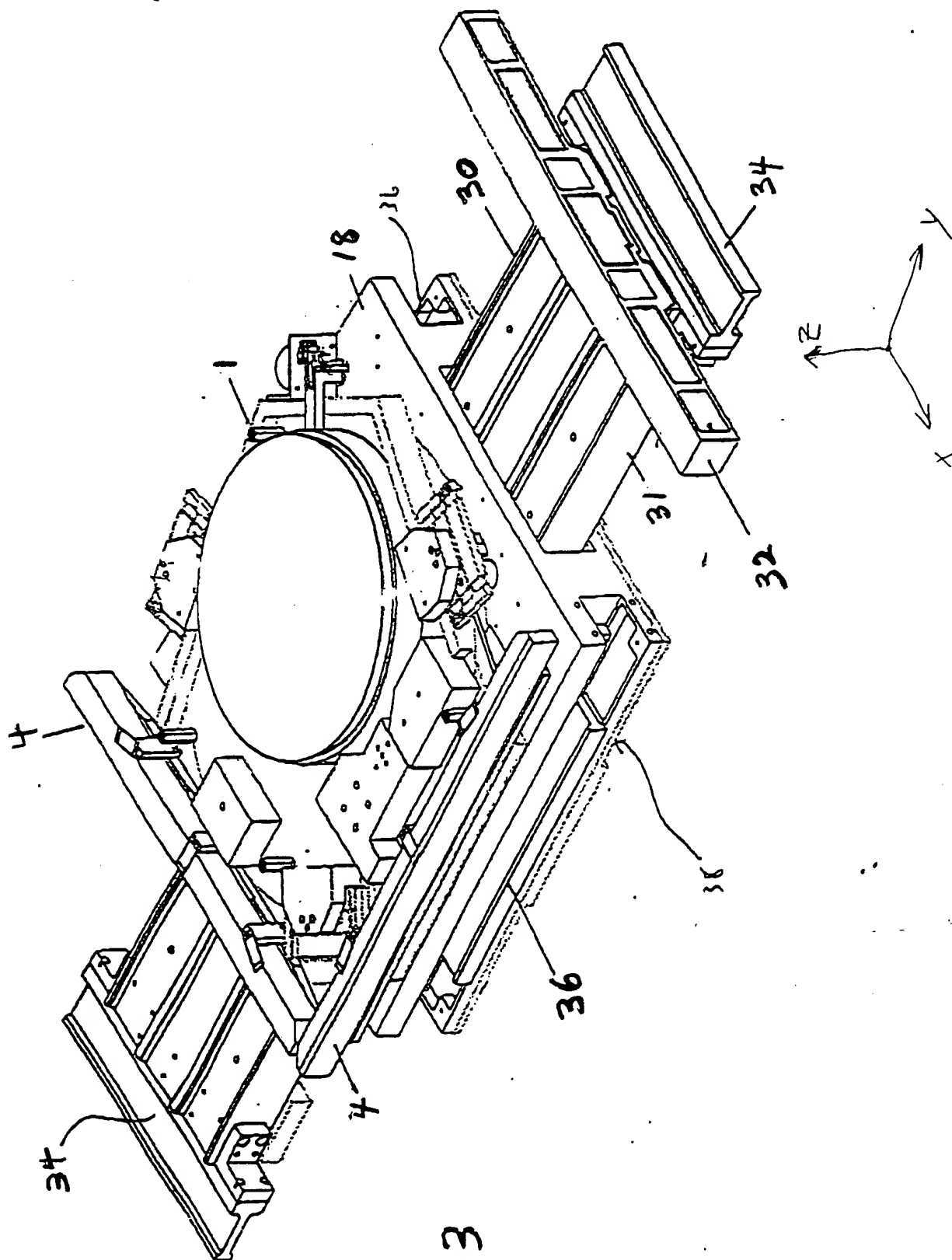
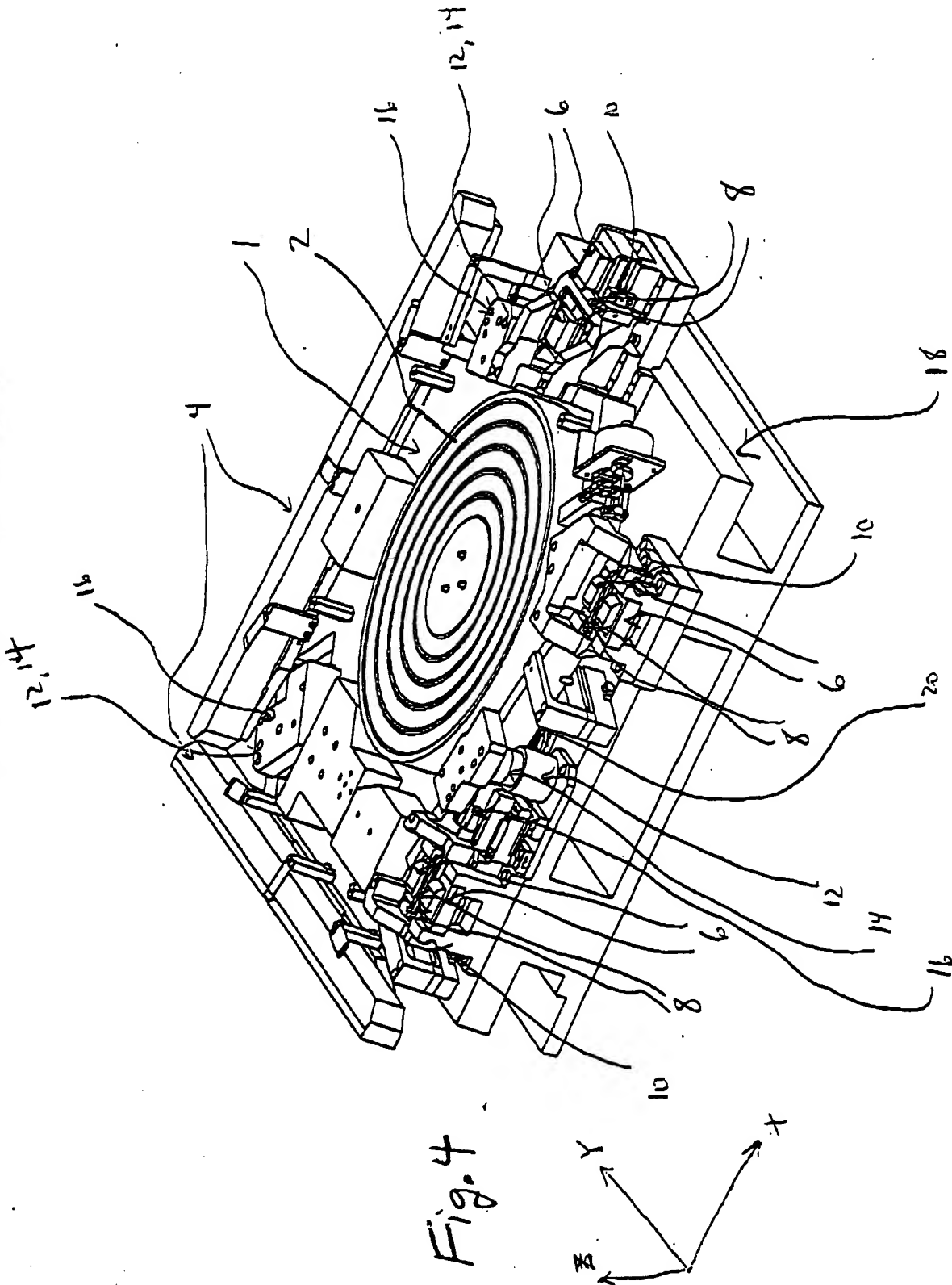


Fig. 3

2

FIG. 4 is a perspective view of the wafer stage 100 in a retracted position. The wafer stage 100 includes a base 10, a wafer 12, and a wafer support 14. The wafer support 14 is positioned above the wafer 12 and is supported by a plurality of magnetic bearings 16. The magnetic bearings 16 are positioned between the wafer support 14 and the base 10. The wafer stage 100 is shown in a retracted position, with the wafer support 14 and the magnetic bearings 16 being moved away from the wafer 12. The wafer stage 100 is shown in a perspective view, with the base 10, the wafer 12, and the wafer support 14 being clearly visible. The magnetic bearings 16 are also clearly visible, and their position relative to the wafer support 14 and the base 10 is shown. The wafer stage 100 is shown in a retracted position, with the wafer support 14 and the magnetic bearings 16 being moved away from the wafer 12. The wafer stage 100 is shown in a perspective view, with the base 10, the wafer 12, and the wafer support 14 being clearly visible. The magnetic bearings 16 are also clearly visible, and their position relative to the wafer support 14 and the base 10 is shown.



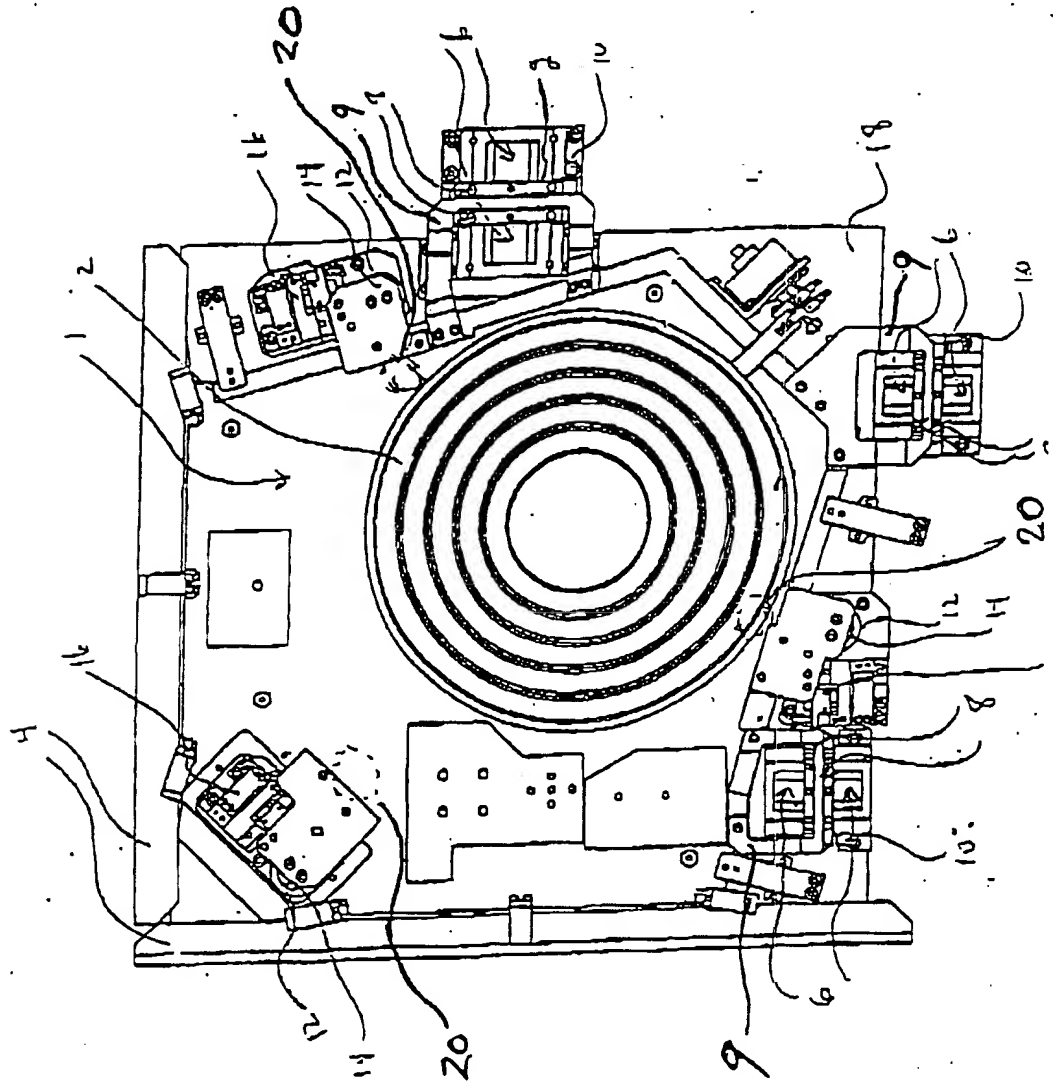
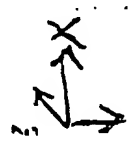
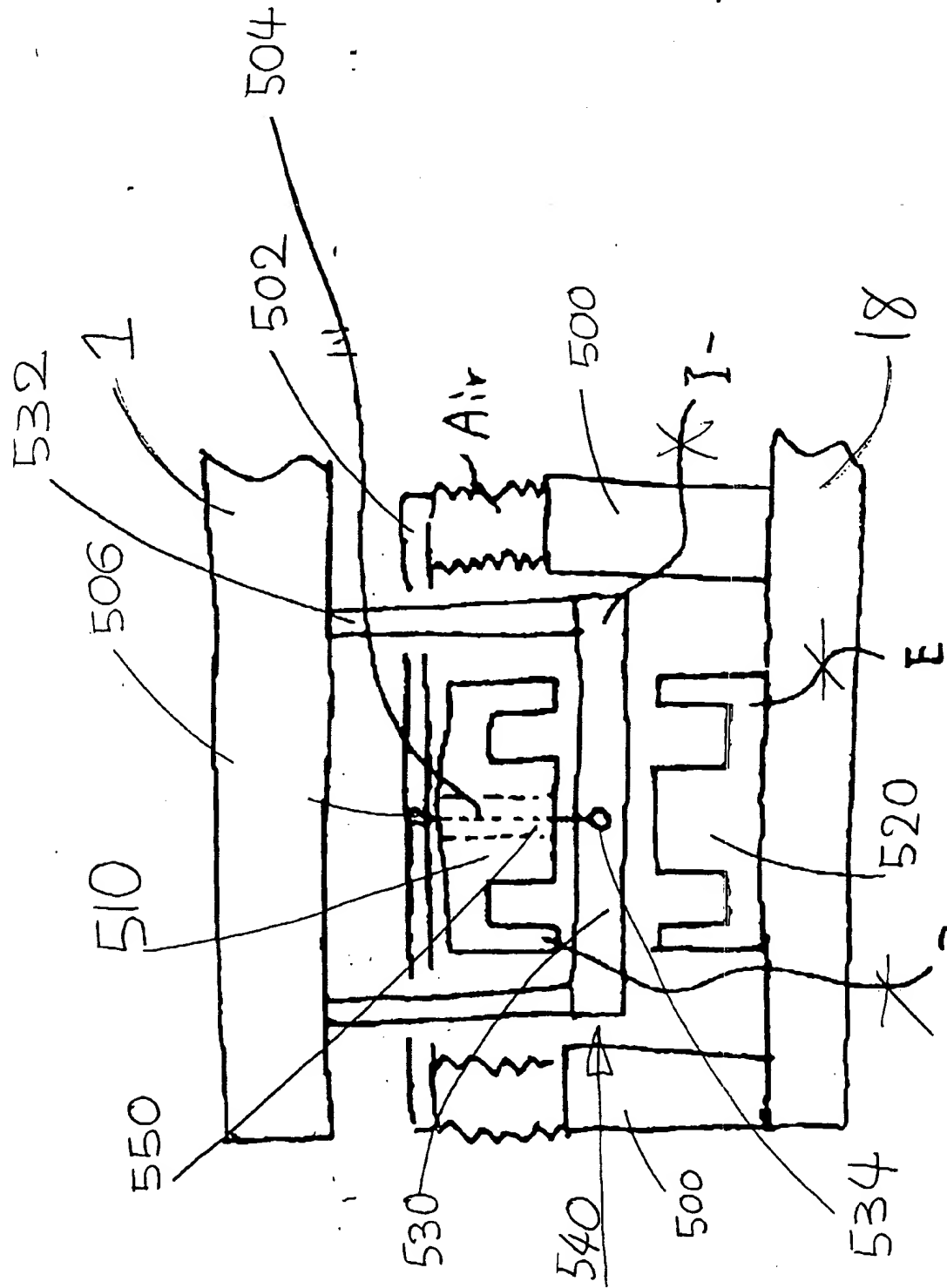


Fig. 5A



★
 FIG. 5B



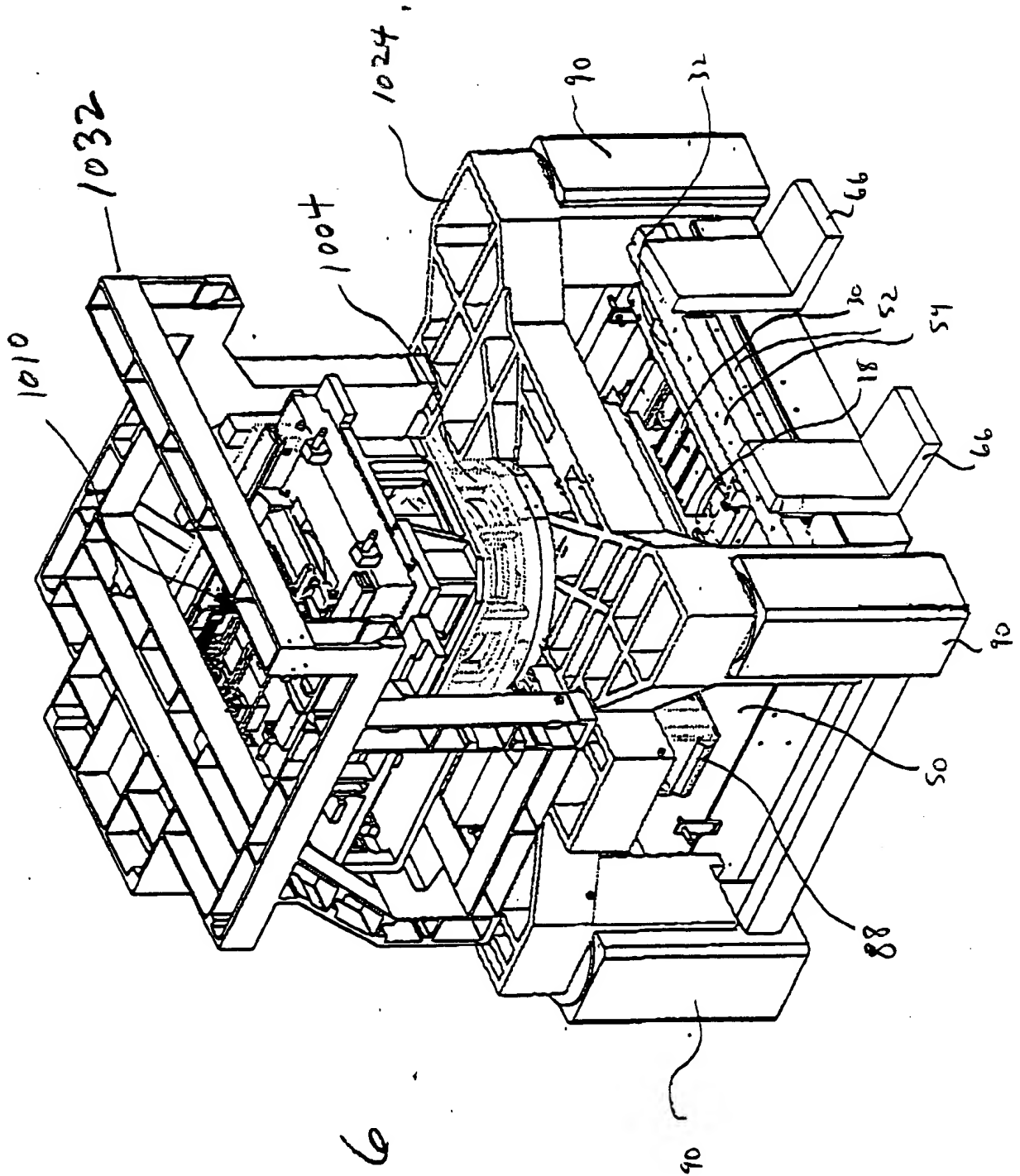


Fig. 6

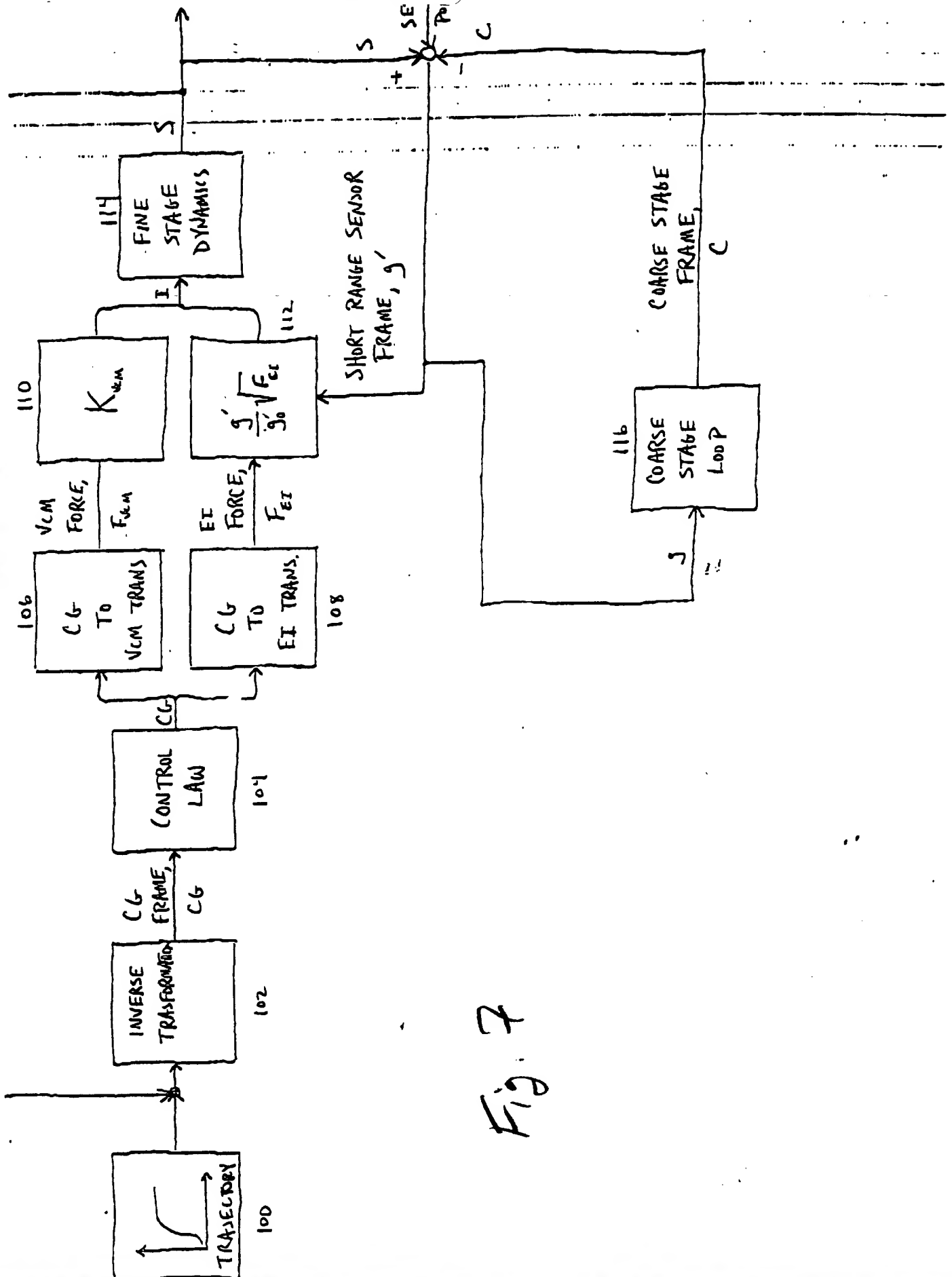
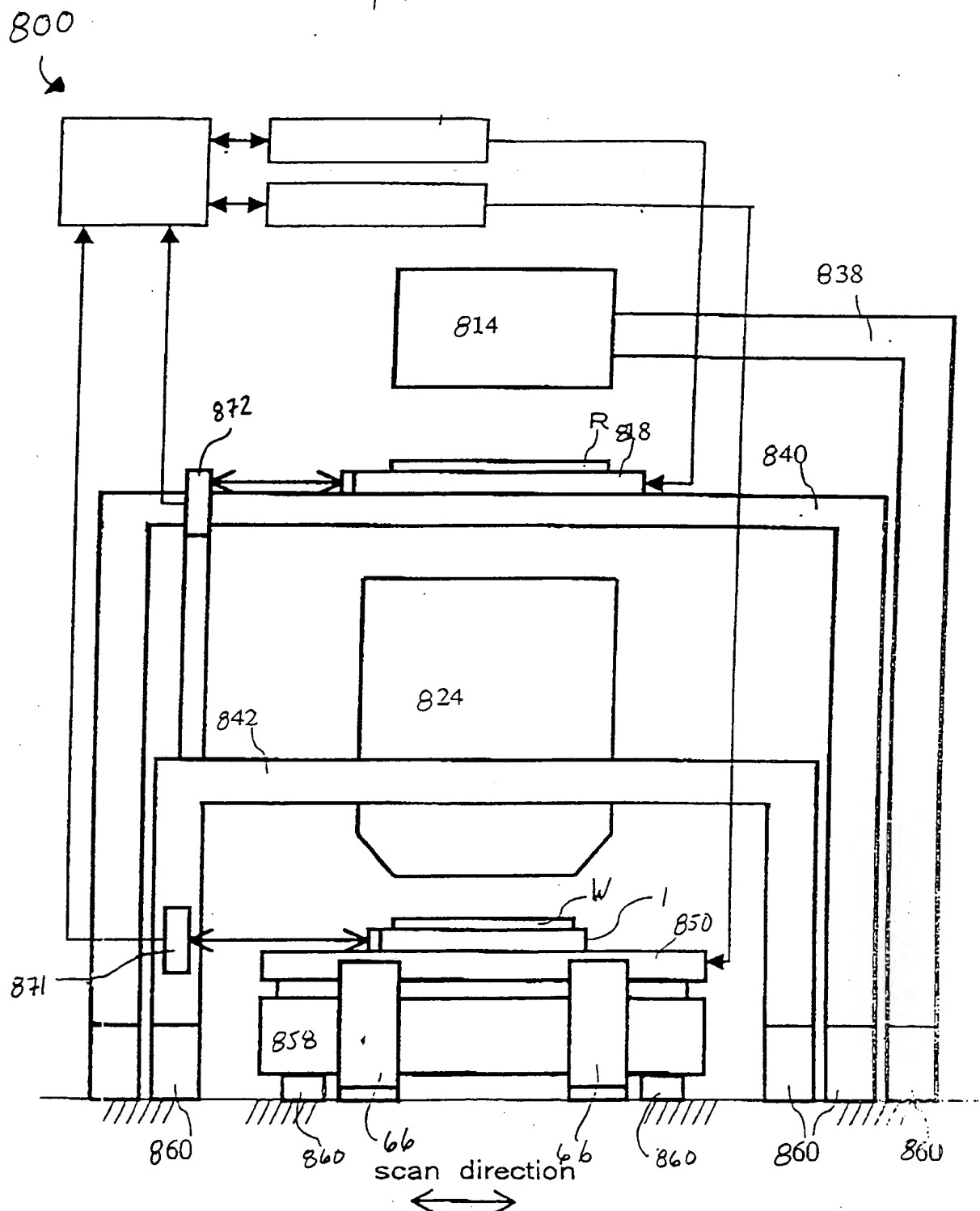


Fig. 7

FIG. 8



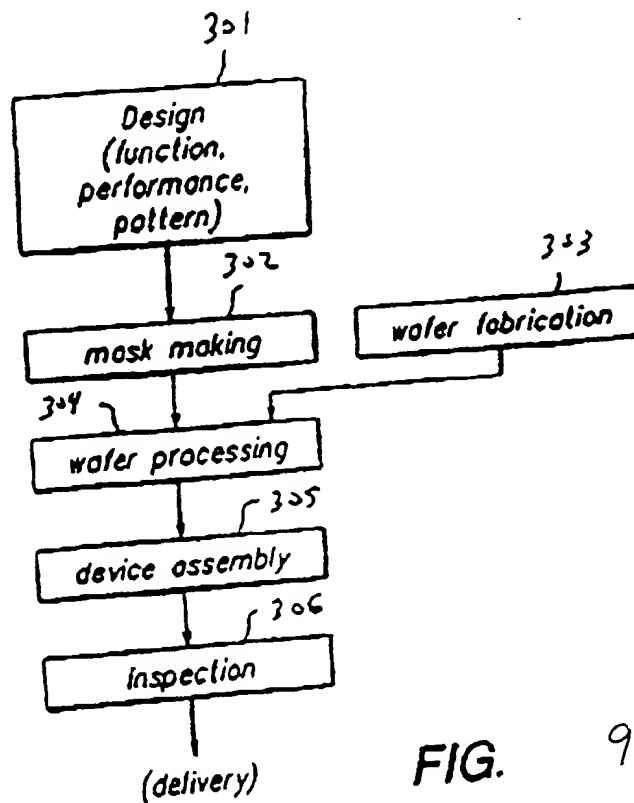


FIG.

9

Fig. 10.

